

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants : Sakae KOYATA et al.

Group Art Unit : 1792

Appl. No. : 10/561,821

Examiner : OLSEN, Allan W.

Filed : February 7, 2007

Confirmation No. : 2851

For : PROCESSING METHOD OF SILICON WAFER

SUPPLEMENTAL AMENDMENT

Commissioner for Patents
U.S. Patent and Trademark Office
Customer Service Window, Mail Stop Amendment
Randolph Building
401 Dulany Street
Alexandria, VA 22314

Sir :

Supplemental to the Amendment filed on August 28, 2009 in response to the Office Action of May 28, 2009, please amend the above-identified application as follows to correct inadvertent errors in claims 5 and 9:

Amendments to the Claims are reflected in the listing of claims beginning on page 2.

Remarks begin on page 5.